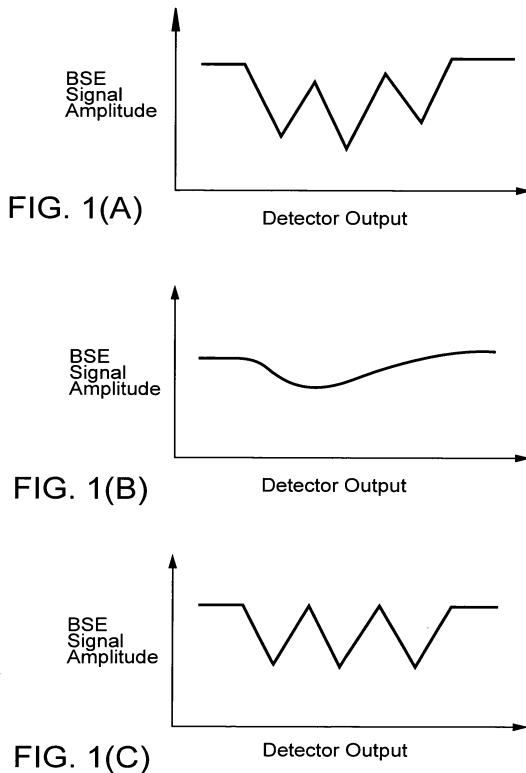
Donald L. Stephens Jr., Klarquist Sparkman, LLP, 121 SW Salmon St., Suite 1600, Portland, Oregon 97204, (503) 595-5300; Inventor: Hirayanagi; Title: ALIGNMENT-MARK DETECTION METHODS AND DEVICES FOR CHARGED-PARTICLE-BEAM MICROLITHOGRAPHY, AND MICROELECTRONIC-DEVICE MANUFACTURING METHODS COMPRISING SAME;

Attorney Docket No.: 4641-55447-01;
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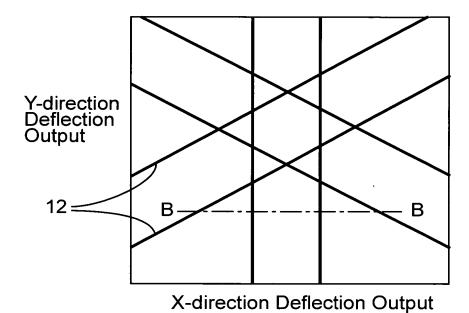


FIG. 2(A)

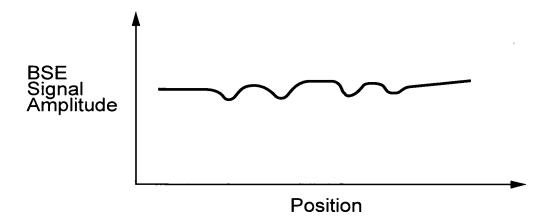


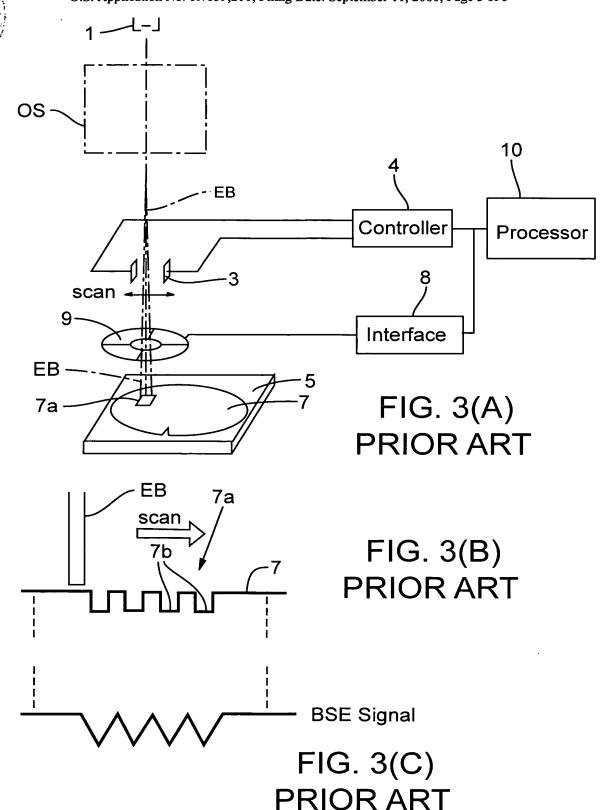
FIG. 2(B)

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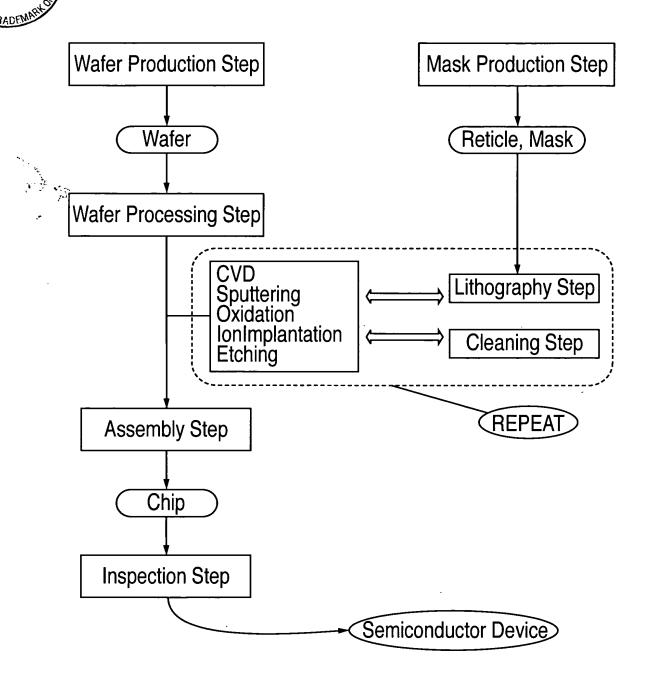


FIG. 4

Donald L. Stephens Jr., Klarquist Sparkman, LLP, 121 SW Salmon St., Suite 1600, Portland, Oregon 97204, (503) 595-5300; Inventor: Hirayanagi; Title: ALIGNMENT-MARK DETECTION METHODS AND DEVICES FOR CHARGED-PARTICLE-BEAM MICROLITHOGRAPHY, AND MICROELECTRONIC-DEVICE MANUFACTURING METHODS COMPRISING SAME;

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Resist Coating Step

Exposure Step

Resist Developing Step

Resist Annealing Step

Lithography Step

FIG. 5